

Sub B3
A1

Claim 4. (amended) A positioning device as claimed in claim 1[, 2, or 3], characterized in that the object holders each comprise a basic part which is guided over the guiding surface and can be coupled to the displacement units, and an object table which is displaceable relative to the basic part by means of an actuator unit of the relevant object holder.

Sub B5
A2

Claim 6. (amended) A lithographic device provided with a radiation source, a mask holder, a focusing unit having a main axis, a characterization unit, and a positioning device, said positioning device comprising a guiding surface extending parallel to an X-direction, which is perpendicular to the main axis, and parallel to a Y-direction, which is perpendicular to the X-direction and the main axis, a first substrate holder and a second substrate holder which are each guided over the guiding surface and are each displaceable parallel to the X-direction and parallel to the Y-direction from a first position into a second position which is near the focusing unit, and a displacement system for displacing the first substrate holder and the second substrate holder over the guiding surface, characterized in that the positioning device of the lithographic device is a positioning device as claimed in claim 1[, 2, 3, 4, or 5], wherein each of the object holders of the positioning device is a substrate